



ASMJP.032AUS

PATENT

7B
84
9/26/02
J.E.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Fukuda et al.) Group Art Unit 1763
Appl. No. : 09/511,934)
Filed : February 24, 2000)
For : THIN-FILM FORMING)
APPARATUS HAVING AN)
AUTOMATIC CLEANING)
FUNCTION FOR CLEANING)
THE INSIDE)
Examiner : R. Kackar)

RECEIVED
SEP 25 2002
TC 1700 MAIL ROOMAMENDMENT AFTER FINAL

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action mailed July 1, 2002 (Paper number 8), please amend the above-captioned application as follows:

IN THE CLAIMS:

Please amend Claim 1 as follows:

- B1
gry
B
1. (Twice amended) A thin film forming apparatus comprising:
a reaction chamber for forming at a film formation temperature a thin film on a workpiece placed on a susceptor provided in the reaction chamber, said susceptor being made of aluminum nitride and provided with a heater for heating the workpiece, said reaction chamber being provided with a conveyer for loading and unloading the workpiece into and from the reaction chamber; and
a cleaning device for cleaning unwanted deposits adhering to the inside of the reaction chamber at predetermined intervals, said cleaning device comprising: